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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of

New York, New York

Akira IZUMI et al.

Date: January 20, 2004

Serial No.: 10/690,912

Group Art Unit: ---

Filed: October 22, 2003

Examiner: ---

For: SUBSTRATE PROCESSING METHOD AND SUBSTRATE PROCESSING
APPARATUS

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

SUBMISSION

Sir:

Submitted herewith is a copy of art together with a form listing the same for the
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Respectfully submitted,

Max Moskowitz

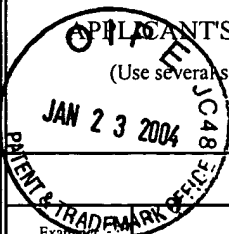
Name of applicant, assignee or
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MM:mjb
Enclosures

 <p>APPLICANT'S ART CITATION (Use several sheets if necessary)</p>		Application 10/690,912		OFGS File No. P/1250-264		
		Applicant Akira IZUMI et al.				
		Filing Date October 22, 2003		Group Art Unit ---		
U.S. PATENT DOCUMENTS						
Examiner Initial	Document Number	Date MM-YYYY	Name	Class	Sub- class	Filing Date If Appropriate
	US-5,932,022	08-1999	Linn et al.	134	2	
	US-5,934,566	08-1999	Kanno et al.	239	398	
	US-					
	US-					
	US-					
	US-					
	US-					
FOREIGN PATENT DOCUMENTS						
	Document Number	Date MM-YYYY	Country	Class	Sub- class	Translation Yes No
	10-256211 /	09-1998	Japan			X
	2003-282527 /	10-2003	Japan			X
	8-078647 /	03-1996	Japan			X
	2001-007067 /	01-2001	Japan			X
	2688293 /	08-1997	Japan			X
	11-340175 /	12-1999	Japan (corresponds with U.S. Patent No. 5,932,022 cited herein)			X
	8-318181 /	12-1996	Japan (corresponds with U.S. Patent No. 5,934,566 cited herein)			X
OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)						
Examiner		Date Considered				
<small>EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP § 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to the applicant.</small>						